IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

n re the Application of:

Keum Joo LEE, et al:

Serial No. 09/955,126

Art Unit:

1746

Examiner: Michail Kornakov

Filed:

September 19, 2001

Confirmation No.

8415

For:

METHOD OF CLEANING DAMAGED LAYERS AND POLYMER RESIDUE FROM

SEMICONDUCTOR DEVICE

Atty. Docket No. 259/011

AMENDMENT UNDER 37 C.F.R. §1.111

Commissioner for Patents P.O. Box 1450 Alexandria, Va. 22313-1450

Sir:

In response to the Office Action mailed September 11, 2003, please amend the subject application as follows: